

Notice of References Cited	Application/Control No. 10/662,162		Applicant(s)/Patent Under Reexamination HEFFNER ET AL.	
	Examiner B. Chen		Art Unit 1792	Page 1 of 1

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
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*	B	US-6,884,290	04-2005	Swain et al.	117/68
*	C	US-6,533,916	03-2003	Puetter et al.	205/188
*	D	US-2006/0124349	06-2006	Fujimura et al.	174/256
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NON-PATENT DOCUMENTS

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	V	Takeno, Takanori, et al., "Electrically conductive properties of tungsten-containing diamond-like carbon films". Diamond and Related Materials, Volume 15, Issues 11-12, November-December 2006, pp. 1902-1905.
	W	Miyagawa, Soji, et al. "Electrically Conductive Diamond-Like Carbon Coatings Prepared by Plasma-Based Ion Implantation with Bipolar Pulses". New Diamond Front Carbon Technology (2006). (BIB DATA ONLY)
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.